



Inventor: Mathew S. Cooper

Title: Physical Vapor Deposition Components and Methods of Formation

Assignee: Micron Technology, Inc.

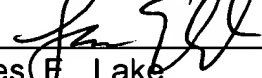
Docket No. H0001190 (4016)

**INFORMATION DISCLOSURE STATEMENT**

References – See Attached Form PTO-1449

The attached form PTO-1449 is submitted in compliance with 37 CFR § 1.56. Copies of the cited art are included. No admission is made regarding whether all the submitted references are prior art.

Respectfully submitted,

Dated: 13 Jan 2005 Attorney:   
James E. Lake  
Reg. No. 44,854

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. H0001190 (4016)	SERIAL NO. 09/699,897			
<div style="position: relative; height: 100px;"> <div style="position: absolute; top: 0; left: 0; width: 100%; height: 100%; border: 1px solid black; border-radius: 50%; text-align: center; color: black; font-weight: bold; font-size: 1.2em;"> OIPES JAN 14 2005 PATENT &amp; TRADEMARK OFFICE </div> </div>				LIST OF ART CITED BY APPLICANT <small>(Use several sheets if necessary)</small>				
				APPLICANT Mathew S. Cooper				
				FILING DATE October 27, 2000	GROUP 1753			
U.S. PATENT DOCUMENTS								
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate		
AA	6,123,783	09/2000	Bartholomeusz et al					
AB	5,334,267	08/1994	Taniguchi et al					
AC								
AD								
AE								
AF								
AG								
AH								
AI								
AJ								
AK								
AL								
FOREIGN PATENT DOCUMENTS								
		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AM							
	AN							
	AO							
	AP							
	AQ							
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)								
	AR							
	AS							
	AT							
EXAMINER				DATE CONSIDERED				
<small>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</small>								